## Notice of References Cited

Application/Control No. 10/039,663



Applicant(s)/Patent Under Reexamination EFLAND ET AL.

Examiner

Leonardo Andújar

Art Unit 2826

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## **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-5,468,993	11-1995	Tani, Koji	257/676
	В	US-5,973,554	10-1999	Yamasaki et al.	327/564
	С	US-			
	D	US			
	Е	US-			
	F	US-			
	G	US-			
	Н	US-			
	ı	US-			
	J	US-			
	κ	US-			
	L	US-			
	М	US-			

## FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	Z			_		
	0					
	Р					
	Q					
	R					
	S					
	Т					

## **NON-PATENT DOCUMENTS**

	HON-I ATENT DOCUMENTO					
*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
	U	Wolf et al., Silicon Processing for the VLSI Era, Lattice Press, volume 1, pages 857-858.				
	٧					
	w					
	х					

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.